

20th Anniversary of KSDT
KISM 2022
Korean International Semiconductor Conference on Manufacturing Technology 2022
November 13-16, 2022 | Paradise Hotel Busan (Haeundae Beach), Busan, Korea

Session Title:	[TF1] Analysis II
Session Date:	November 15 (Tue.), 2022
Session Time:	09:30-10:50
Session Room:	Room F (Sicily Room, 1F)
Session Chair:	Prof. Jun Ho Lee (Kongju Nat'l Univ., Korea)

[TF1-1] [Invited] 09:30-10:00

SEM Technology for 3D Measurement of High Aspect Ratio Structure

Younghoon Sohn and Jaehyung Ahn (Samsung Electronics Co., Ltd., Korea)

[TF1-2] 10:00-10:20

Atom Probe Tomography for Characterization of Semiconductor Processing

A. D. Giddings (AMETEK Korea Co., Ltd., Korea)

[TF1-3] 10:10-10:30

Development of a Low Energy Scanning Electron Microscope Using a Monochromator with Cylindrical Lenses for Nano Imaging and Analysis

Takashi Ogawa (KRISS, Korea), Yu Yamazawa, Tsutomu Saito, Junichi Katane (Hitachi High-Tech Corp., Japan), In-Yong Park (KRISS, Korea), and Toshihide Agemura (Hitachi High-Tech Corp., Japan)

[TF1-4] 10:30-10:50

Through-Focus Optical Scanning Microscopy for Defect Detection and Classification Below Optical Resolution

Jun Ho Lee, Ji Yong Joo, Jung Bin Lee, Ji Won Park (Kongju Nat'l Univ., Korea), Oh-Hyung Kwon (NEXTIN Inc., Korea), and Junhee Jeong (NEXTIN Inc., Korea)